

Docket Number: 081468-0356680

PATENT APPLICATION

Client Reference: P-1823.020-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

HANS VAN DER LAAN, et al.

Group Art Unit: UNKNOWN

Application No.: 10/590,352

Examiner: UNKNOWN

Filed: August 23, 2006

Confirmation No.: 8164

For: METHOD TO DETERMINE THE VALUE OF PROCESS PARAMETERS BASED
ON SCATTEROMETRY DATA

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

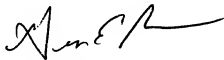
Sir:

Pursuant to 37 CFR 1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Copies of non-patent literature are included. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Applicants respectfully request the Examiner return an initialed copy of the enclosed Form PTO-1449 to Applicants with the next Office communication to indicate that the references have been considered, per MPEP § 609.

This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

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Client Ref.

081468

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**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: VAN DER LAAN et al.

Appln. No.: 10/590,352

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Page 1 of 1

Examiner: Unknown

Group Art Unit: Unknown

U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR					
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					
	IR					

FOREIGN PATENT DOCUMENTS

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	JR							
	KR							
	LR							
	MR							
	NR							
	OR							
	PR							
	QR							
	RR							
	SR							

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

TR	Allgair et al., "Spectroscopic CD Offers Higher Precision Metrology for sub-0.18 µm Linewidth Control", Yield Management – Yield Acceleration Strategies for the Semiconductor Industry", Vol. 4, Issue 2, Summer 2002, pp. 8-13						X	
UR	Wold et al., "Nonlinear PLS Modeling", Chemometrics and Intelligent Laboratory Systems", 7, pp. 53-65 (1989)						X	
VR	Valley et al., "Approaching New Metrics for Wafer Flatness: An Investigation of the Lithographic Consequences of Wafer Non-Flatness", Metrology, Inspection, and Process Control for Microlithography XVIII, Proceedings of SPIE, Vol. 5375 (2004)						X	
WR								
XR								
YR								

Examiner

Date Considered:

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.